

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)	ATTY. DOCKET NO. 58620.00010	SERIAL NO. <u>10/830,133</u> New Application
	APPLICANT SBERVEGLIERI et al	
	FILING DATE April 23, 2004	GROUP <u>2856</u> Not yet assigned

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
AA						

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

/JF/	AL	Sberveglieri et al, "Highly Sensitive and Selective NO _x and NO ₂ Sensor Based on Cd-doped SnO ₂ Thin Films," Sensors and Actuators B. 4, 1991, pages 457-461.
	AM	Sberveglieri et al, "A new technique for the preparation of highly sensitive hydrogen sensors based on SnO ₂ (Bi ₂ O ₃) thin films," Sensors and Actuators B, 5, 1991, pages 253-255.
	AN	Sberveglieri et al, "A new technique for growing porous SnO ₂ (Bi ₂ O ₃) thin films as hydrogen gas sensors," Journal of Materials Science Letters 10, 1991, pages 602-604.
		Sberveglieri et al, "A novel PVD technique for the preparation of SnO ₂ thin films as C ₂ H ₅ OH Sensors," Sensors and Actuators B, 7, 1992, pages 721-726.
		Sberveglieri et al, "R.G.T.O: A New Technique for Preparing SnO ₂ Sputtered Thin Film as Gas Sensors." IEEE, vol. 5, 1991, pages 165-168.
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		Ferroni et al, "Gas-Sensing Applications of W-Ti-O-based nanosized thin films prepared by r.f. reactive sputtering", Sensors and Actuators B, 44, 1997, pages 499-502.
		Faglia et al, "Electrical and structural properties of RGTO-In ₂ O ₃ sensors for ozone", Sensors and Actuators B 57, 1997, pages 188-191
		Comini et al, "Carbon monoxide response of molybdenum oxide thin films deposited by different techniques", Sensors and Actuators B 68, 2000, pages 168-174.
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/JF/		Comini et al, "Production and characterization of titanium and iron oxide nano-sized thin films", J. Mater. Res., vol. 16, no. 6, June 2001, pages 1559-1564.

EXAMINER /John Fitzgerald/	DATE CONSIDERED 08/10/2007
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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APPLICANT

Giorgio SBERVEGLIERI et al.

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EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
/JF/	AA	4,338,281	July 6, 1982	Treitinger et al.			
/JF/	AB	4,389,373	June 21, 1983	Linder et al.			
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FOREIGN PATENT DOCUMENTS

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO PART.		
	AG								
	AH								
	AI								
	AJ								
	AK								

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

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